

Proton beam, electron beam, and femtosecond laser writing lithography method for semiconductor microstructures

Abstract Category

Materials Physics

Primary author: GUGA, Aluwani (University of Cape Town)

Co-authors: Dr KOTSEDI, Chester (iThemba Labs/NRF); Dr MONGWAKETSI, Nametso (iThemba Labs/NRF); Prof. BLUMENTHAL, Mark (University of Cape Town)

Presenter: GUGA, Aluwani (University of Cape Town)

Track Classification: Physics Research